

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

**PATENT RECEIVED
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Applicant: MAJIMA et al.

Examiner: VO, Hai

FEB 18 2004

Serial No.: 09/890,550

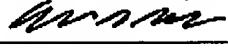
Group No.: 1771

Filed: January 14, 2002

Title: POROUS SILICON CARBIDE SINTER AND SILICON CARBIDE-METAL COMPOSITE THAT ARE OPTIMAL FOR A WAFER GRINDER TABLE

OFFICIAL**RESPONSE TO OFFICE ACTION****CERTIFICATE OF TRANSMISSION/MAILING**

I hereby certify that this correspondence is being transmitted to the USPTO or deposited with the United States Postal Service with sufficient postage as first class mail in an envelope addressed to: Commissioner for Patents, Alexandria, VA 22313-1450 on 2-18-04.

 Reg. No. 40,764
Mark D. Passler

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

INTRODUCTORY COMMENTS

In reply to the Office Action dated August 18, 2003 in the above-identified application, please enter the following Response.

Remarks/Arguments begin on page 2 of this paper.